



U.S. UTILITY Patent Application

DATE	PATENT DATE
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APPLICATION NO. 09/762985	CONT/PRIOR D F	CLASS 210 156	SUBCLASS 345 48	ART UNIT 1745 763	EXAMINER AHAM
APPLICANTS Volker Becker Franz Laemmle Andrea Schlipf					
TITLE Device and method for etching a substrate using an inductively coupled plasma					

PTO-330  
1289

CLAIMS ALLOWED	
NOTICE OF ALLOWANCE MAILED	
ISSUE FEE	
Amount Due	Date Paid
ISSUE BATCH NUMBER	

Information regarding the processing of this application may be obtained from the United States Patent and Trademark Office, Washington, D.C. 20590, or from the nearest Patent Office.

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